

MiniLab S60M

- **Manual sputter deposition system**
- **Front loading box chamber**
- **Ideal R&D / pilot line production tool**



- **Turbo molecular / rotary vane pumping combination as standard**
- **Simple pump/vent operation takes care of vacuum levels**
- **Manual operation with automated source shutter via film thickness monitor**
- **3" Magnetron flexihead as standard DC / RF compatible**
- **Can populate with upto 4 magnetron heads**
- **Manual gas admission and throttle valve**
- **Variable speed sample rotation stage with quick release boss**
- **Water cooled quartz crystal sensor**
- **Modular design allows upgrade path and flexibility**
- **Requires minimal services (operates off 20A single phase supply)**
- **LOW COST OF OWNERSHIP**